



Inventor: Mathew S. Cooper

Title: Physical Vapor Deposition Components and Methods of Formation

Assignee: Micron Technology, Inc.

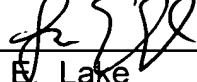
Docket No. H0001190 (4016)

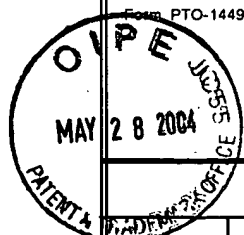
INFORMATION DISCLOSURE STATEMENT

References – See Attached Form PTO-1449

The attached form PTO-1449 is submitted in compliance with 37 CFR § 1.56. Copies of the cited art are included. No admission is made regarding whether all the submitted references are prior art.

Respectfully submitted,

Dated: 28 May 2004 Attorney: 
James E. Lake
Reg. No. 44,854



Form PTO-1449

U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
H0001190 (4016)SERIAL NO.
09/699,897LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)APPLICANT
Mathew S. CooperFILING DATE
October 27, 2000GROUP
2812

U.S. PATENT DOCUMENTS

Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	5,087,297	02/1992	Pouliquen			
	AB	5,456,815	10/1995	Fukuyo et al			
	AC	5,741,377	04/1998	Goyal et al			
	AD	4,832,810	05/1989	Nakamura +			
	AE	5,590,389	12/1996	Dunlop et al			
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM	EP1041170A2	10/2000	EPO				
	AN	WO9961670	12/1999	PCT				
	AO	WO9902750	01/1999	PCT				
	AP	WO9824945	06/1998	PCT				
	AQ	EP0882813	12/1998	EPO				
	AR	WO9910548	03/1999	PCT				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AS		
	AT		
	AU		

EXAMINER

DATE CONSIDERED

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.